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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: OZAKI, Takashi, et al.

Group Art Unit: 1792

Serial No.: 10/528,137

Examiner: MACARTHUR, Sylvia

Filed: December 12, 2005

P.T.O. Confirmation No.: 2307

FOR: SUBSTRATE PROCESSING APPARATUS AND METHOD FOR

MANUFACTURING A SEMICONDUCTOR DEVICE

AMENDMENT UNDER 37 CFR §1.111

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

June 12, 2008

Sir:

In response to the Office Action dated December 14, 2007, extended from March 14, 2008 to June 14, 2008 by a three (3) month Petition for Extension of Time, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 9 of this paper.